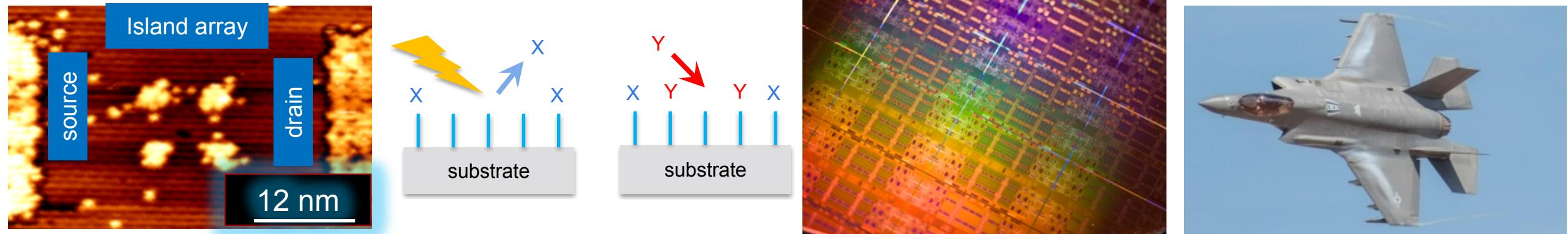


*Exceptional service in the national interest*



# FAIR DEAL GC Technical Overview

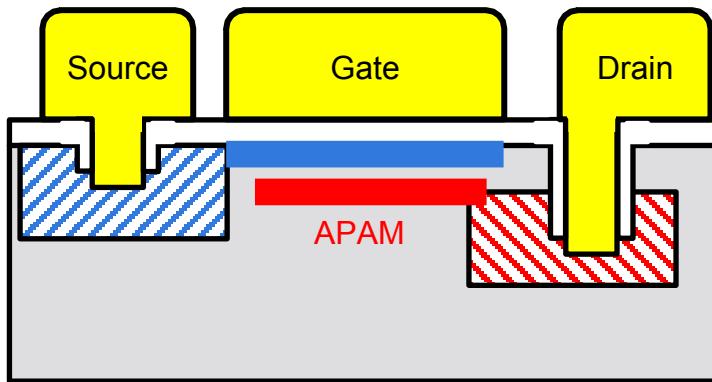
Shashank Misra



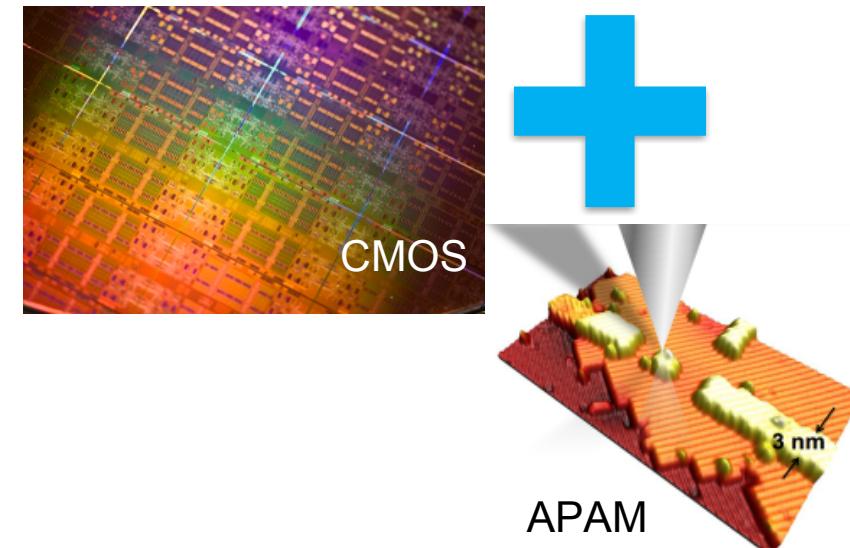
Sandia National Laboratories is a multimission laboratory managed and operated by National Technology and Engineering Solutions of Sandia, LLC, a wholly owned subsidiary of Honeywell International, Inc., for the U.S. Department of Energy's National Nuclear Security Administration under contract DE-NA0003525.

# Overview of EAB #4

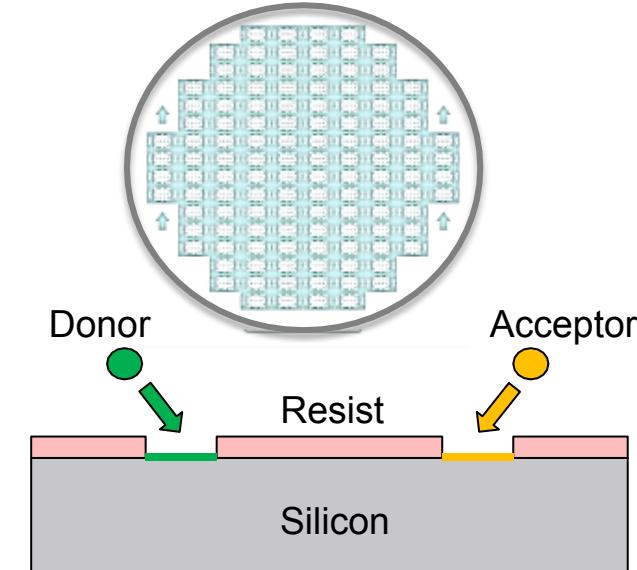
## APAM transistor



## CMOS – APAM integration



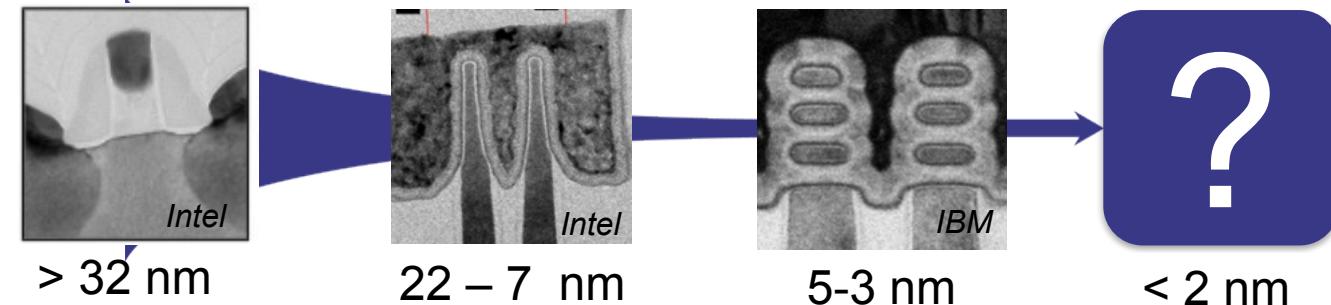
## Manufacturability



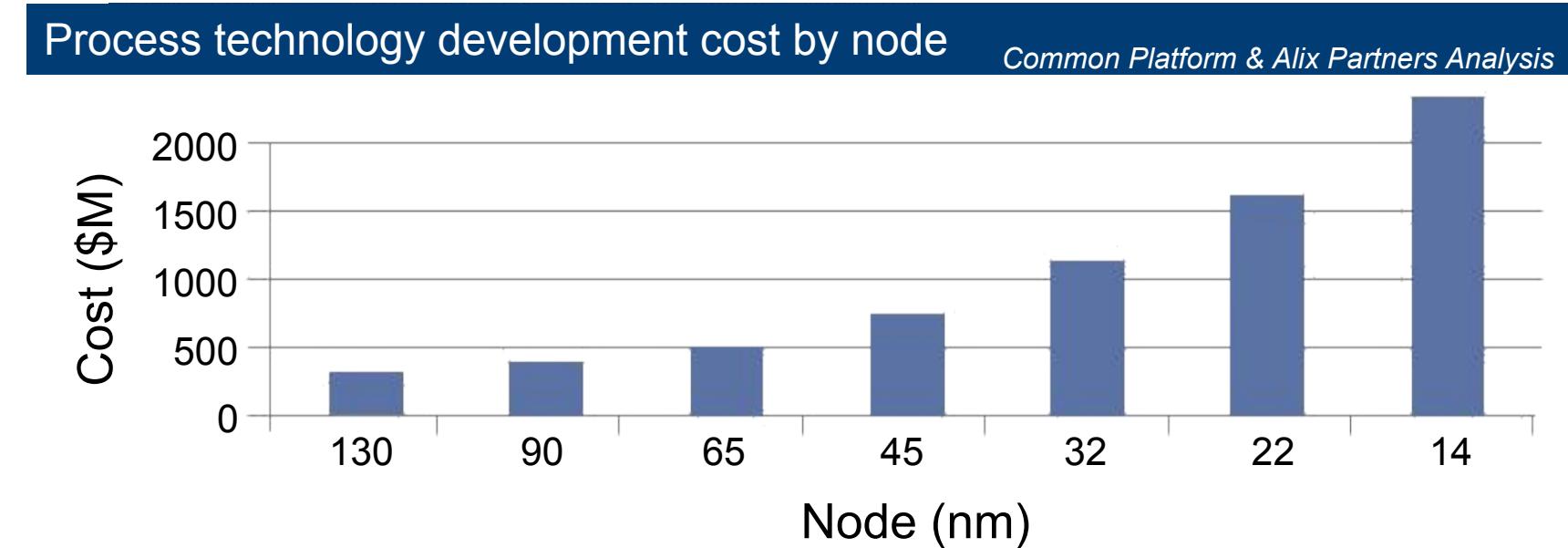
- **Audacious technical goals accomplished (Day 1)**
- **Established a foundation that is being taken in many directions (Day 2)**
- **We aren't near critical mass. What do we do next? (Board)**

# Where is microelectronics headed?

Historically, shrink transistor  
→ more functionality and  
declining cost



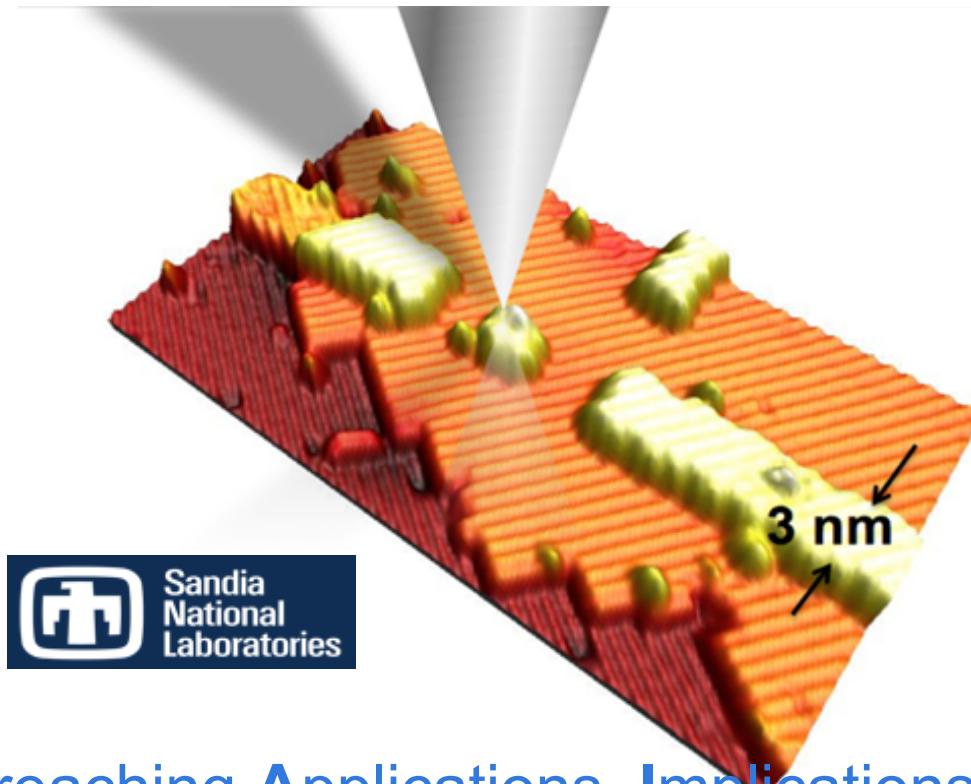
R&D costs rising  
exponentially  
→ Unclear path forward



**Opportunity for non-scalable R&D pathfinding**

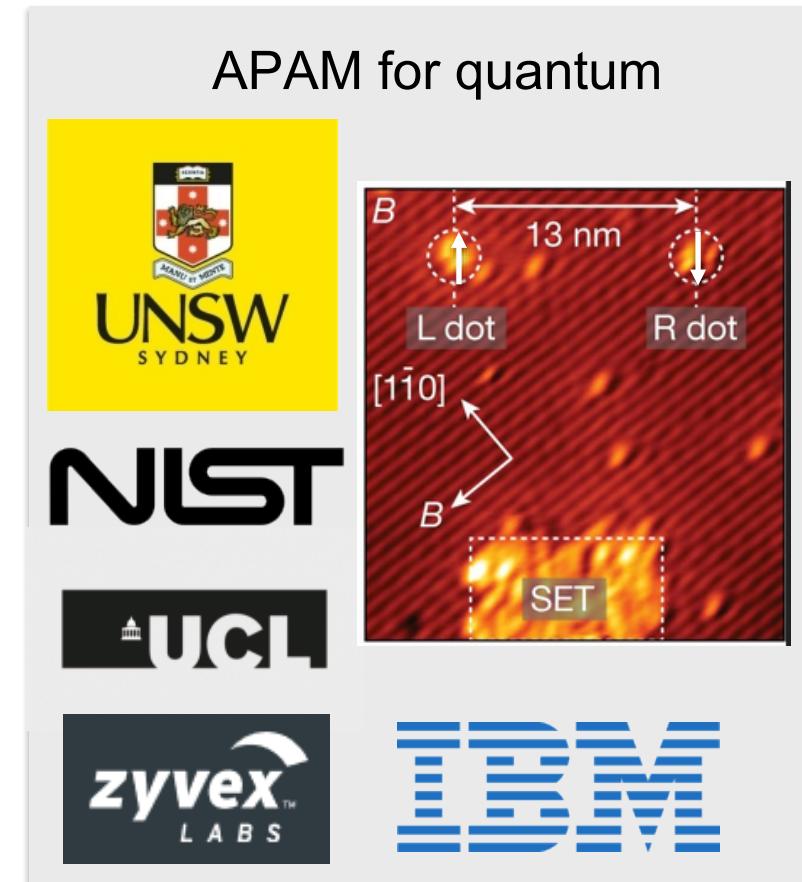
# Atomic Precision Advanced Manufacturing (APAM)

Our mission: To assess the opportunities presented by APAM-enabled devices and processing for the digital microelectronics of the future

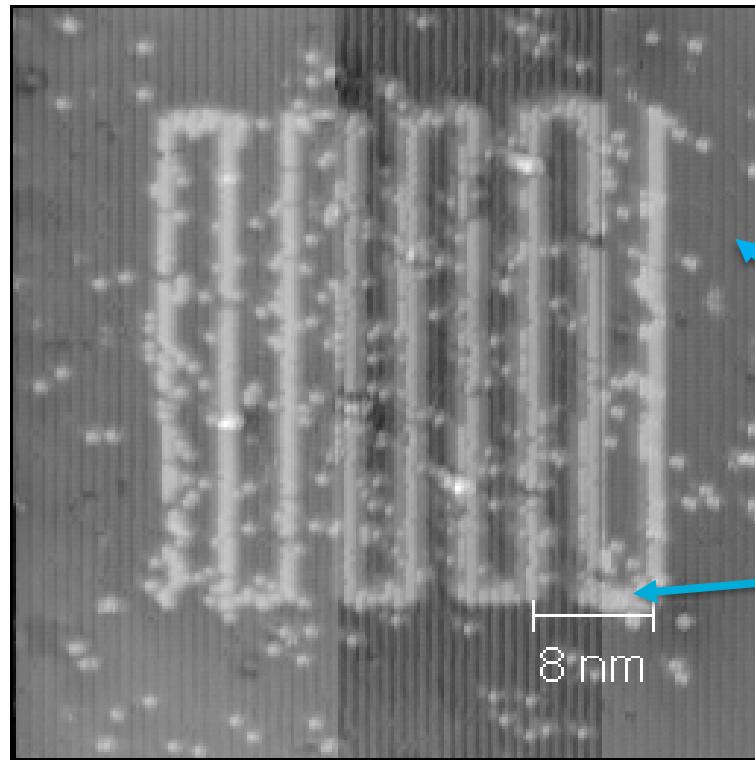


Sandia  
National  
Laboratories

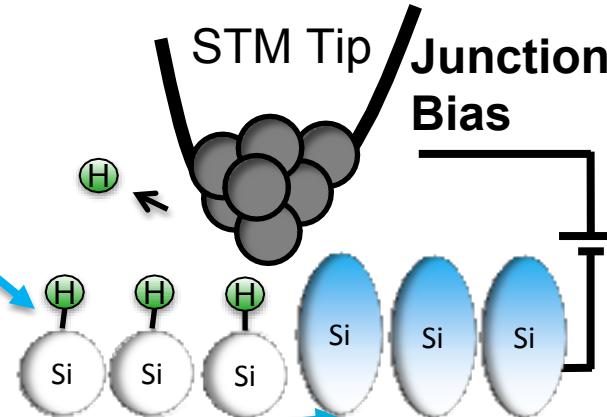
Far-reaching Applications, Implications, and  
Realization of Digital Electronics at the Atomic  
Limit



# How does Atomic Precision Advanced Manufacturing (APAM) work?



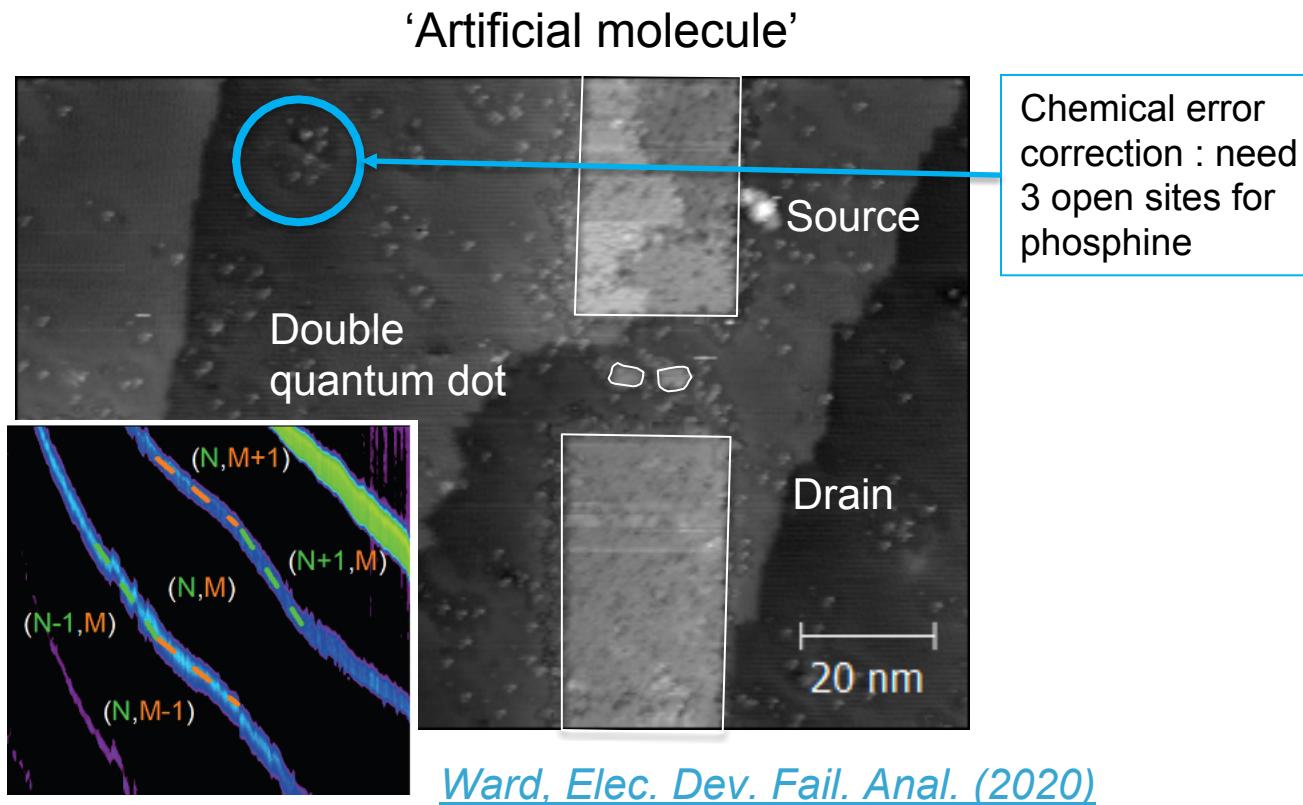
Scanning tunneling microscope (STM)  
can image and pattern the surface



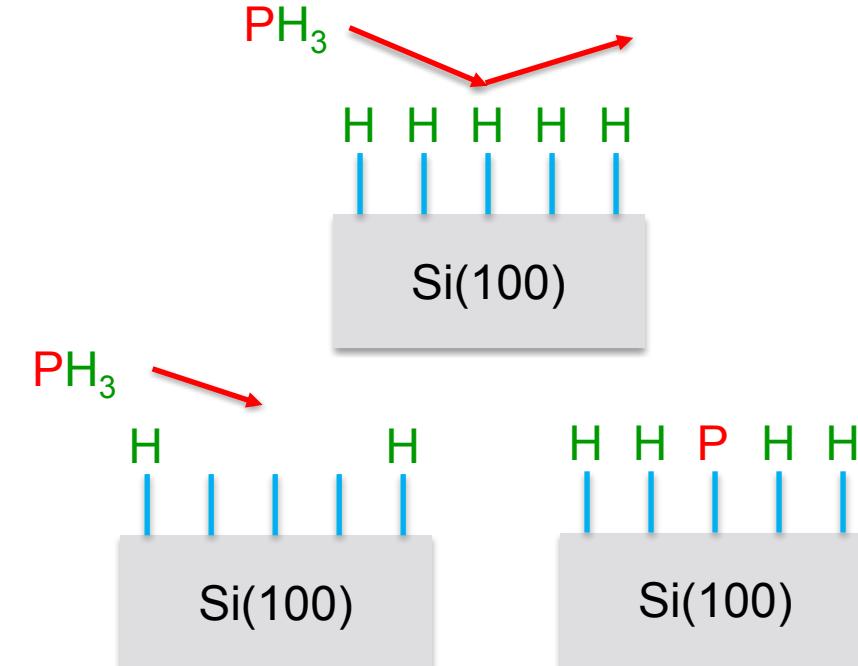
## “Chemical contrast” at Si surface

- Unterminated Si: 1 reactive bond/ atom
- H-terminated Si: unreactive

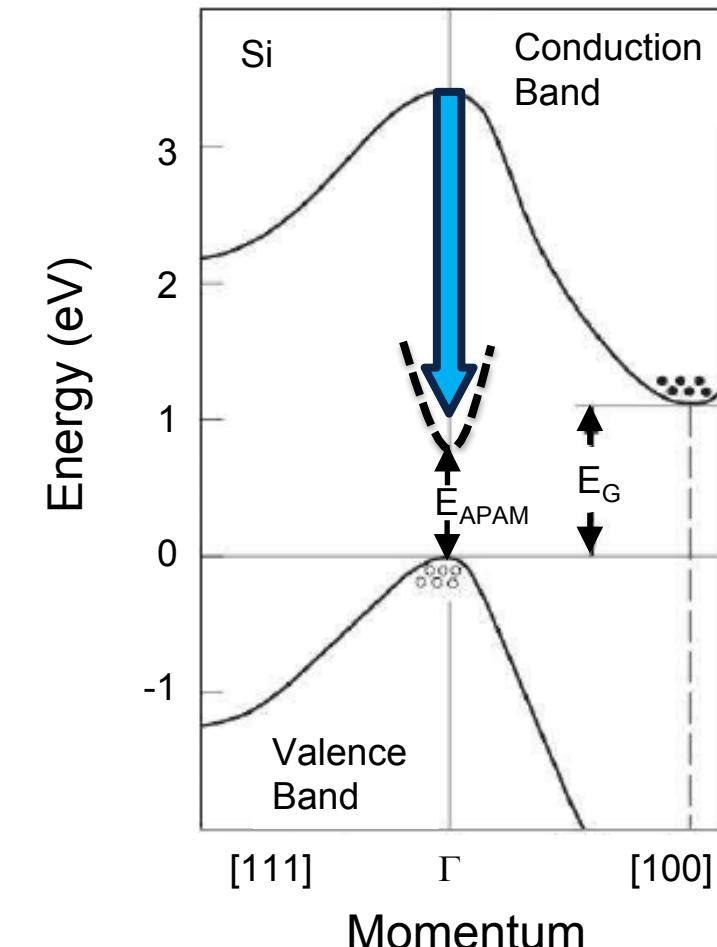
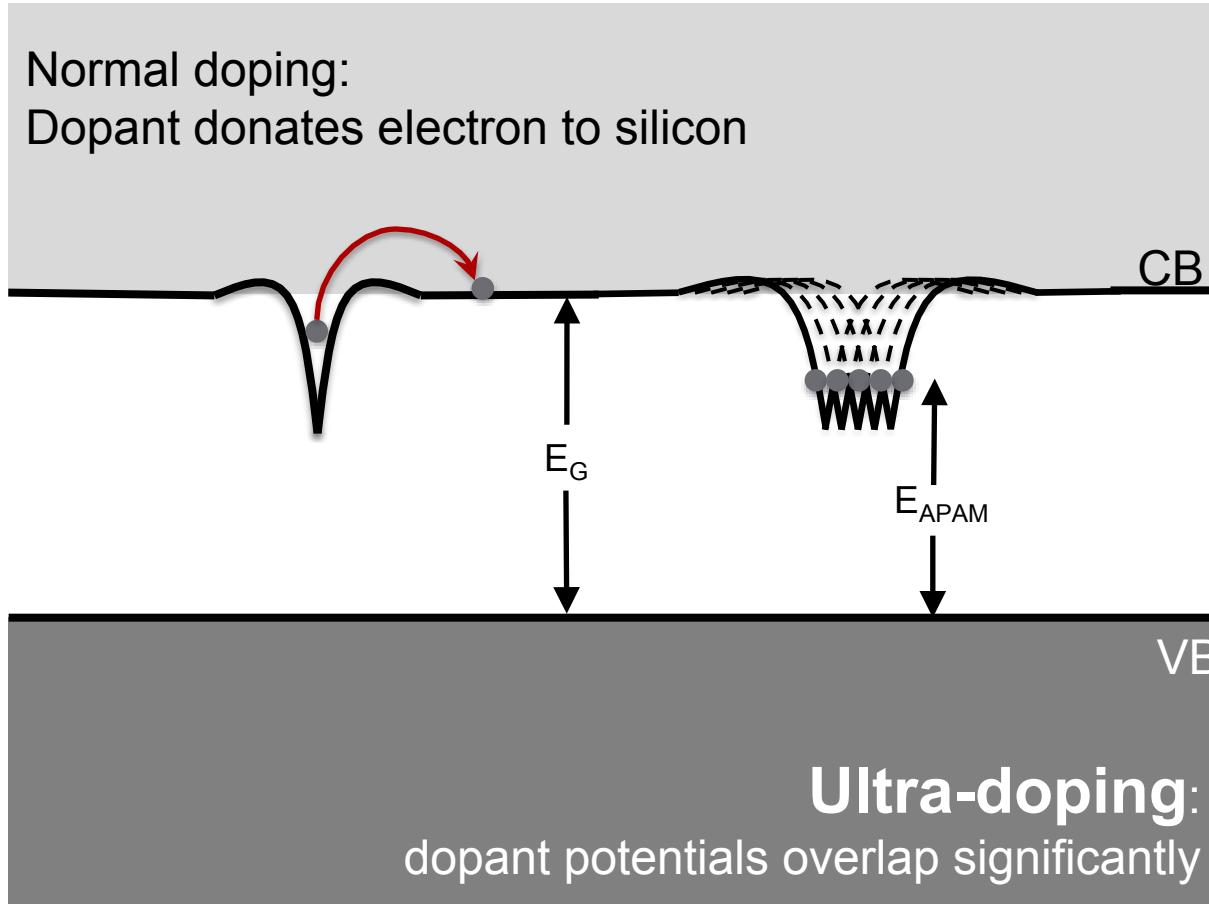
# Doping using phosphine surface chemistry



Phosphorus ‘donates’ an electron to silicon.



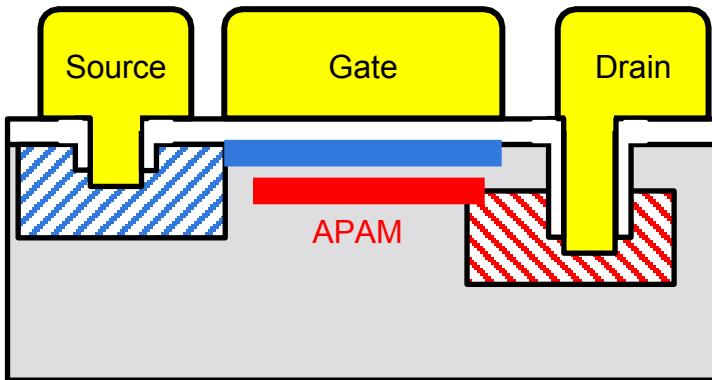
# What does APAM produce that's special?



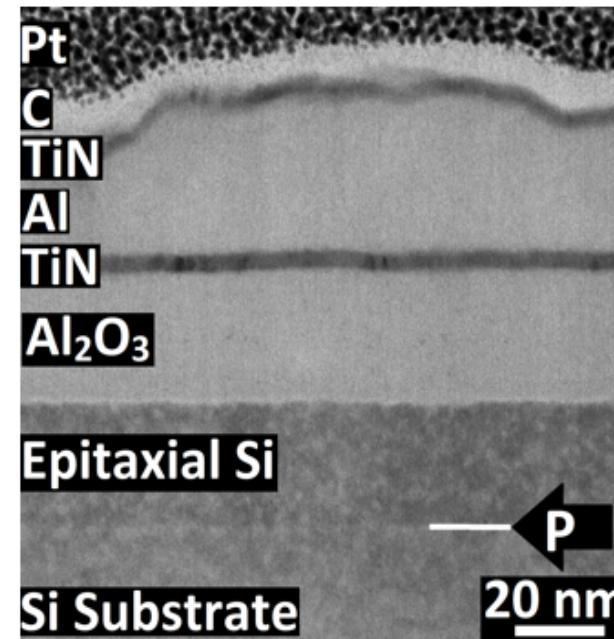
**Fundamental opportunity 3: Fundamentally change electronic structure of silicon**

# Outline

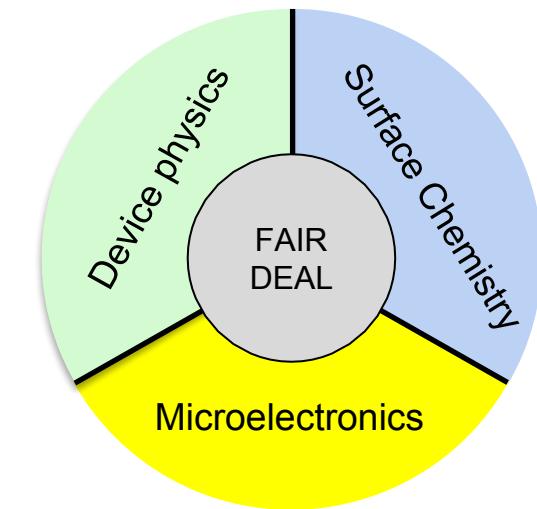
## 1. Goals



## 2. Accomplishments

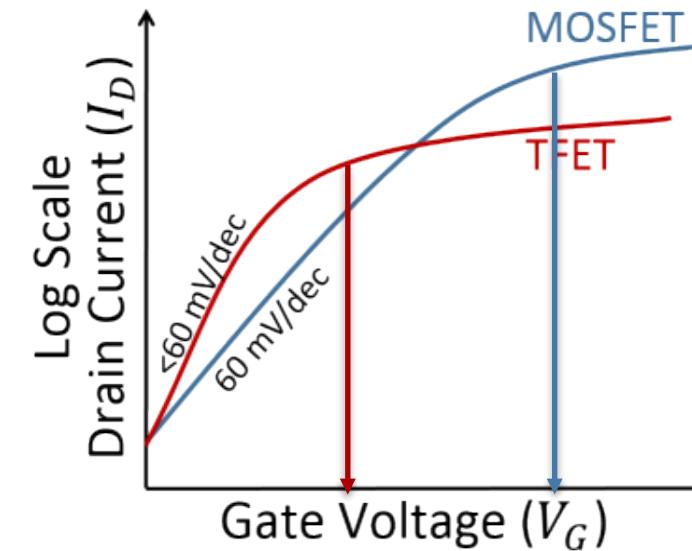
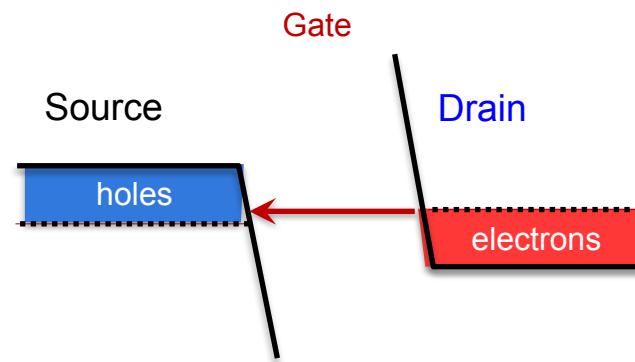
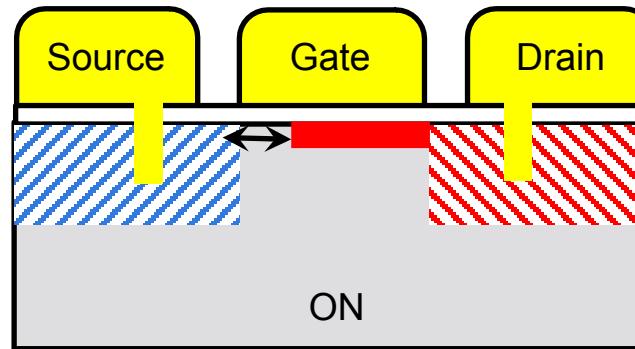


## 3. Our future

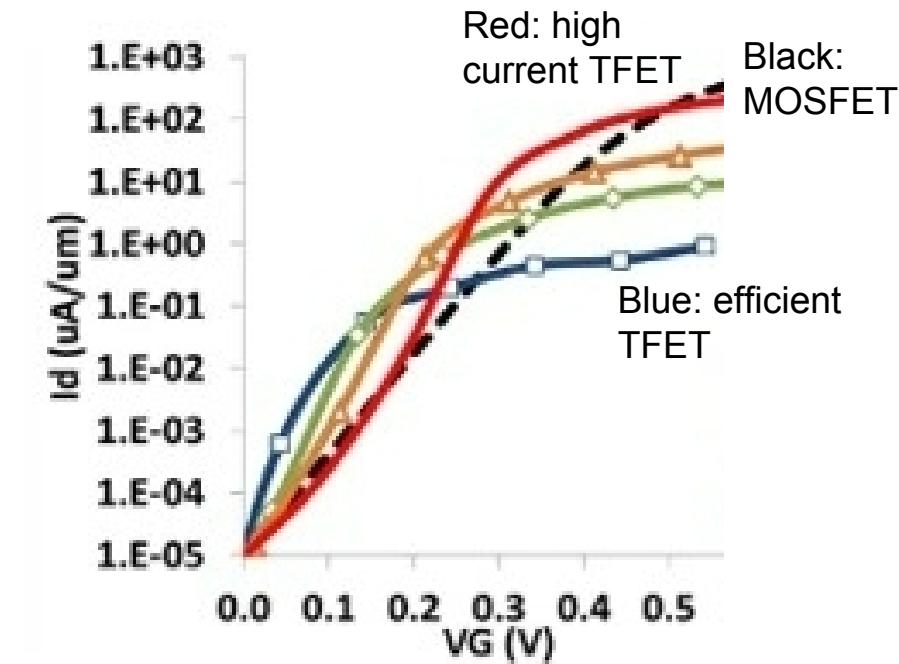


# Technological benefit of atomic-scale control

## Tunnel field effect transistor (TFET)



TFETs 10x energy efficiency **in theory**

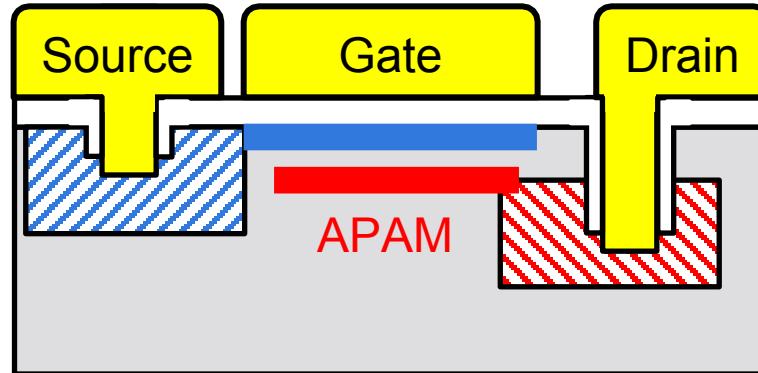


TFETs have not realized their promise **in practice**

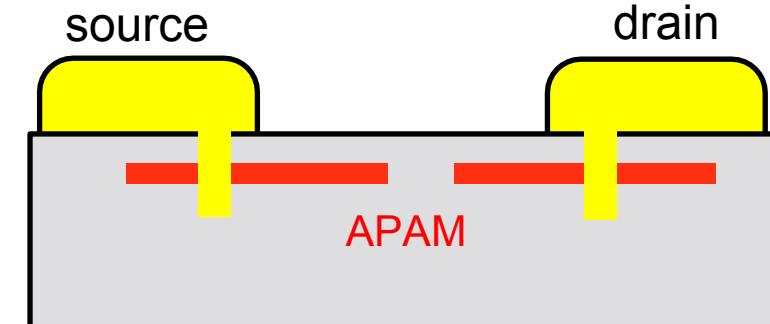
**Explore new transistor technology armed with atomic precision**

# How to overcome limitations to TFETs

APAM TFET



APAM  
(2018)



## APAM-enabled vertical TFET:

- Atomically abrupt doping profile & energy efficiency
- Vertical geometry & current density

## What work needs to be done?

- Missing device components
- Lack of complementary doping type
- Absence of modeling tools to enable design

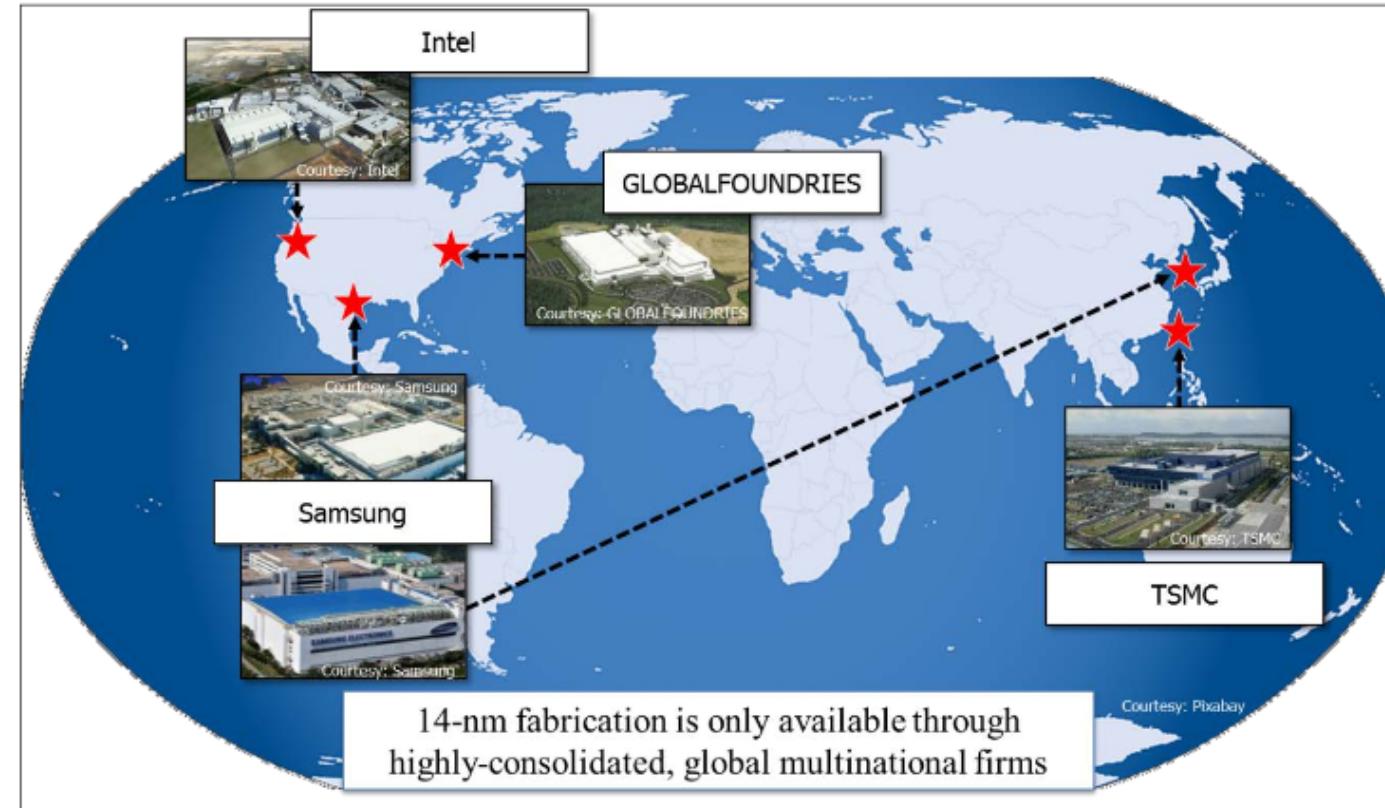
**FD Goal: Before making an APAM transistor, need to establish underlying components**

# Technological benefit of using chemistry for processing

Chemistry-based processing is very flexible – don't need a thermal activation (e.g. implant or epitaxy)

Modern supply chains are global.

Need to protect the USG's information.



Atomic scale – can be used to anticipate future opportunities

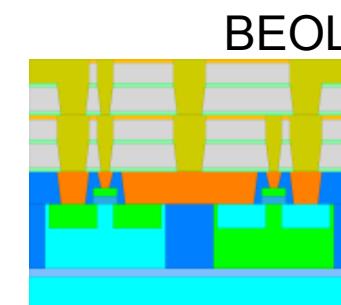
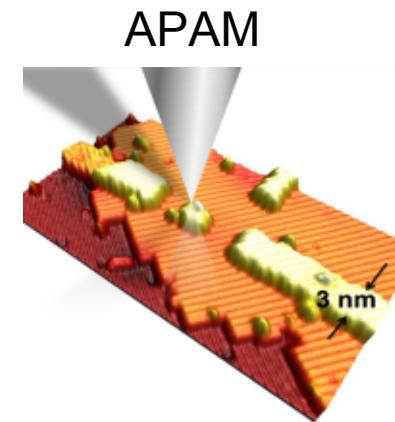
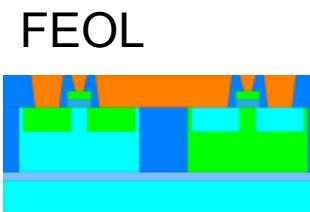
Unusual integration points during manufacturing – new possibilities

**Seek to develop hardware trust and security features**

# APAM – CMOS integration

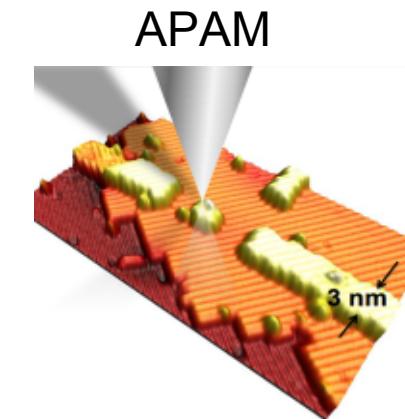
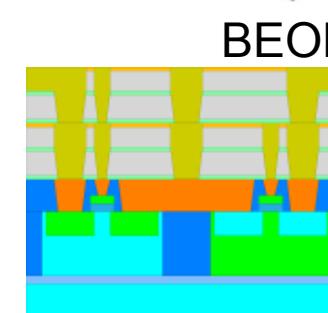
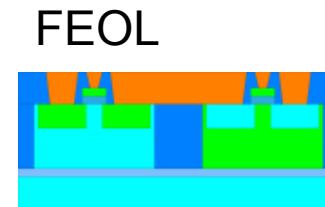
## Goal: Direct integration

- Anticipate future opportunities
- Split fabrication – untrusted FEOL



## Goal: Post-CMOS integration

- Zero trust – untrusted FEOL & BEOL
- Add features outside of typical flow



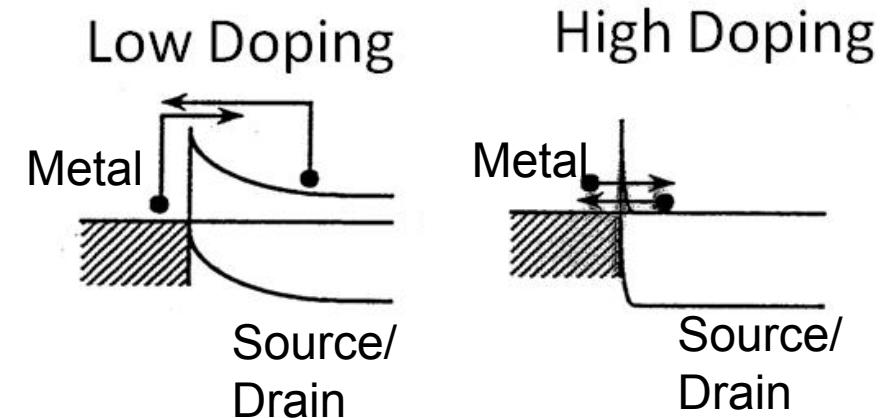
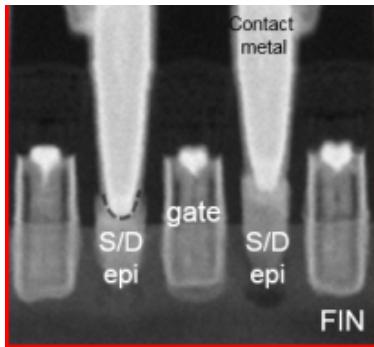
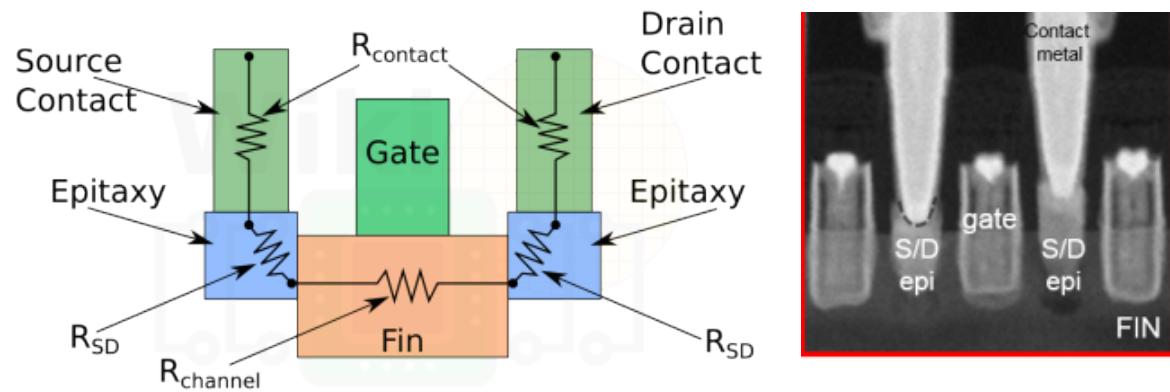
## What work needs to be done?

- Determine insertion point
- New APAM processes
- Robustness of APAM vs. CMOS

**FD Goal: Before making APAM hardware trust & security elements, need to establish underlying integration flows**

# Technological benefit of atomic-scale manufacturing

## Application pull: contact resistance

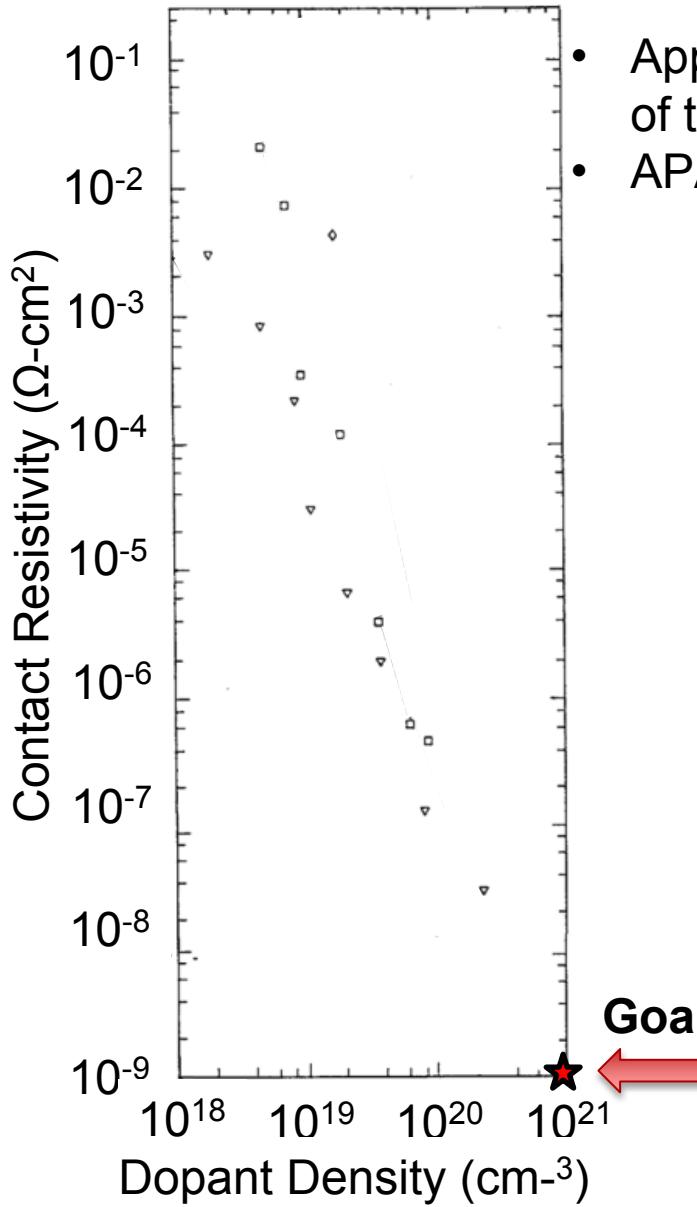


As transistors shrink, channel resistance goes down, but contact resistance goes up

Contact resistance is determined by the size of the speed bump – depends on doping

**APAM dopant density exceeds solid solubility limit**  
**Big change to electronic structure makes for better CMOS contacts**

# APAM manufacturability



- Applied Materials state of the art :  $\sim 4 \times 10^{20} \text{ cm}^{-3}$
- APAM can beat that.



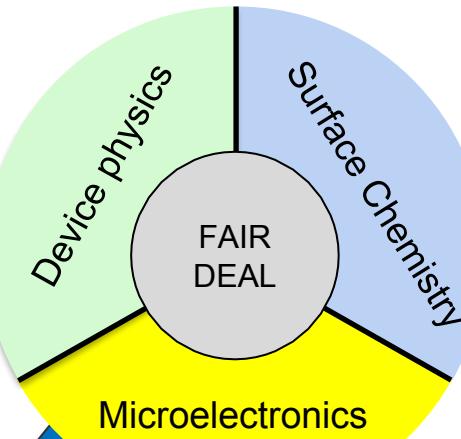
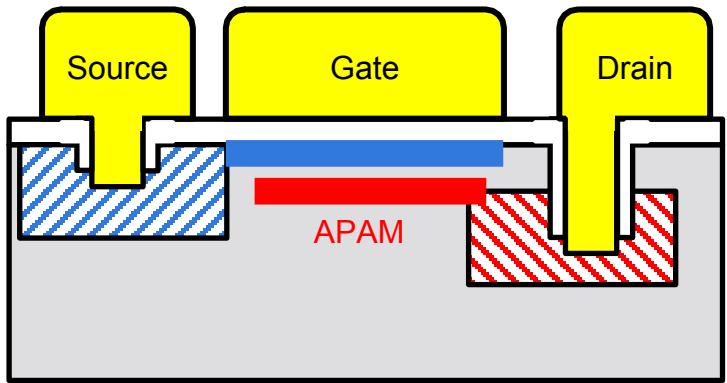
## What's missing?

- 3D doping profiles
- donors & acceptors
- Parallel lithography
- 8" (or larger) wafers

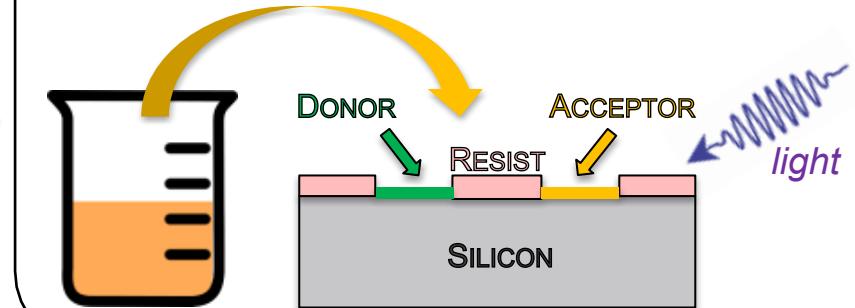
**FD Goal: To pursue many applications, need to expand principles underlying manufacturability**

# Digital electronics at the atomic limit (DEAL)

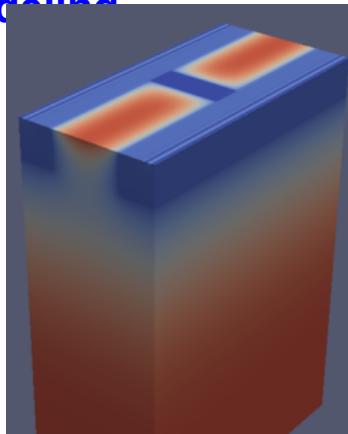
## Thrust 1: APAM-enabled Devices



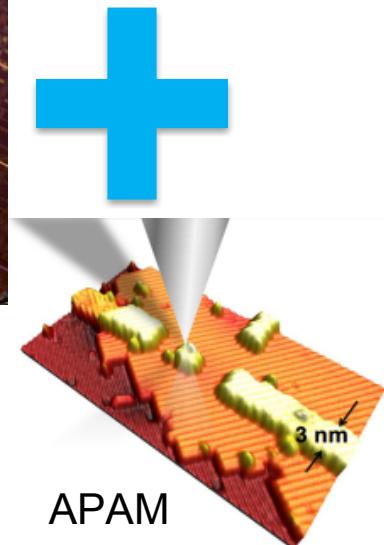
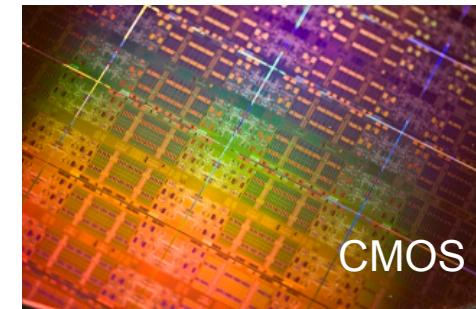
## Thrust 4: APAM toolbox



## Thrust 2: APAM Modeling

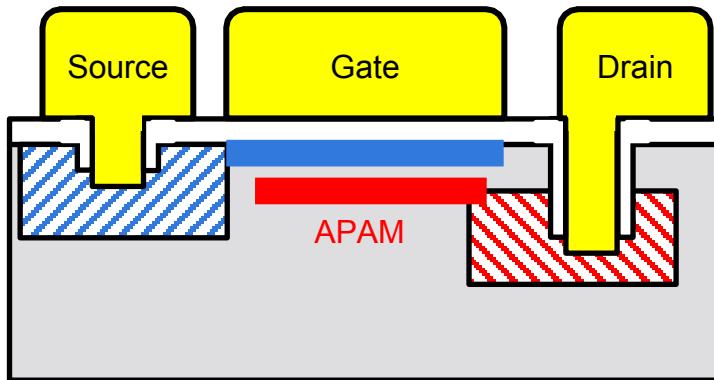


## Thrust 3: CMOS Integration

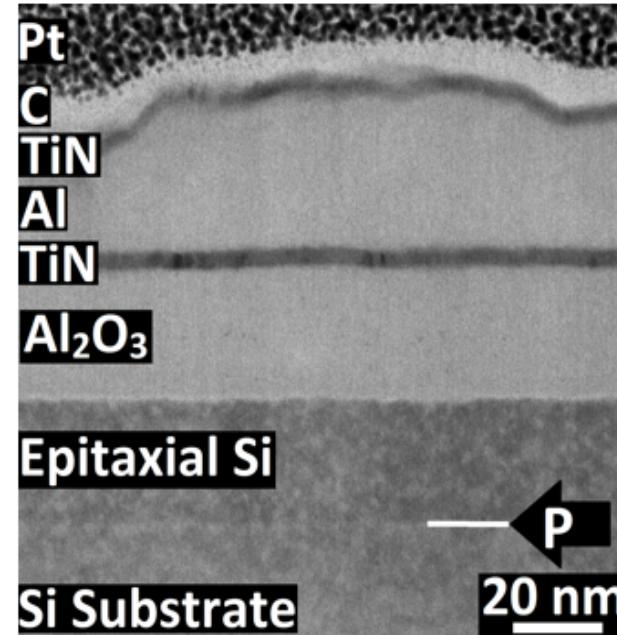


# Outline

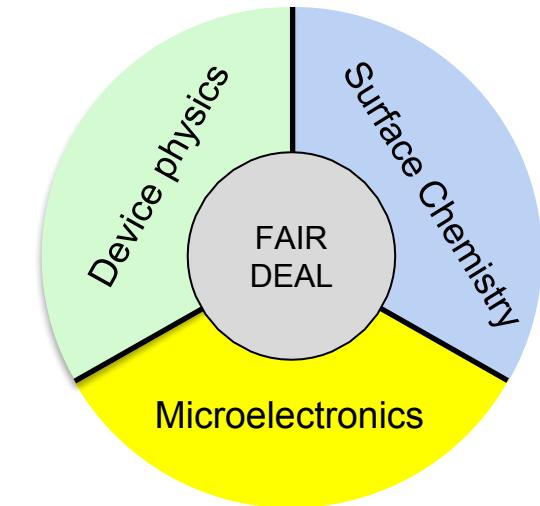
## 1. Goals



## 2. Accomplishments



## 3. Our future

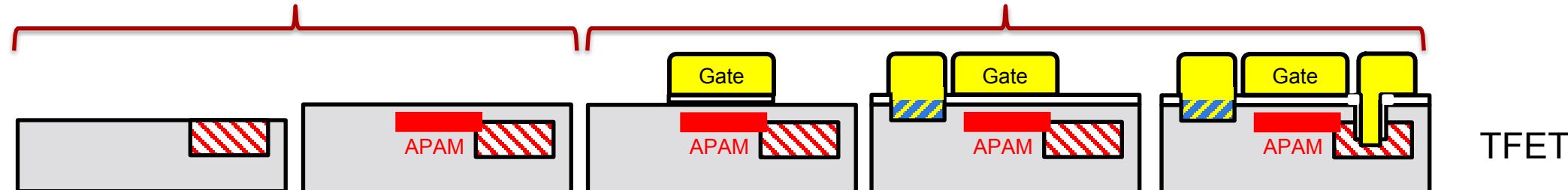


# APAM transistor

Requirements:

Keep existing device structures on chip intact

Add device structures while preserving APAM



Task-level components:

APAM CMOS integration prep

Surface gate

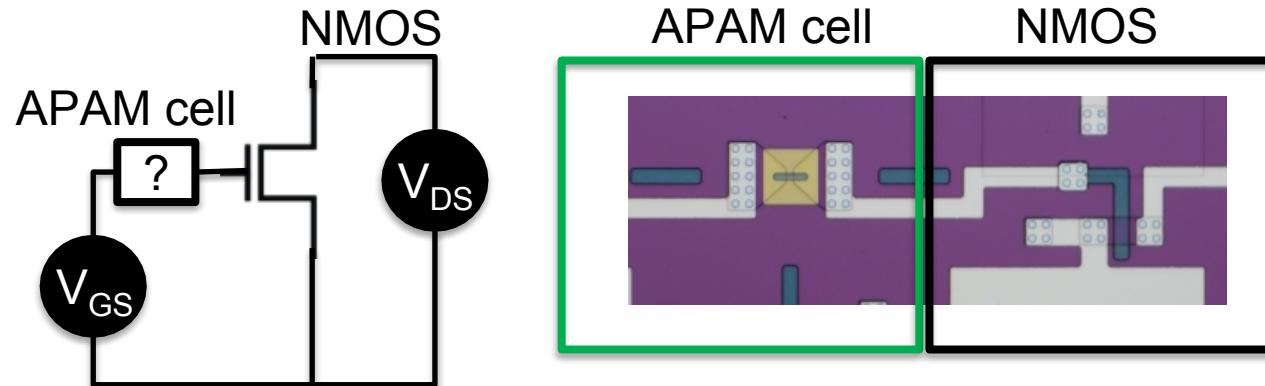
Silicide contact

Room-temp operation

Semiclassical and quantum modeling used throughout for device designs, and to understand data

**We have established relevant device components & workflows, and an APAM TFET is imminent**

# APAM-CMOS Integration

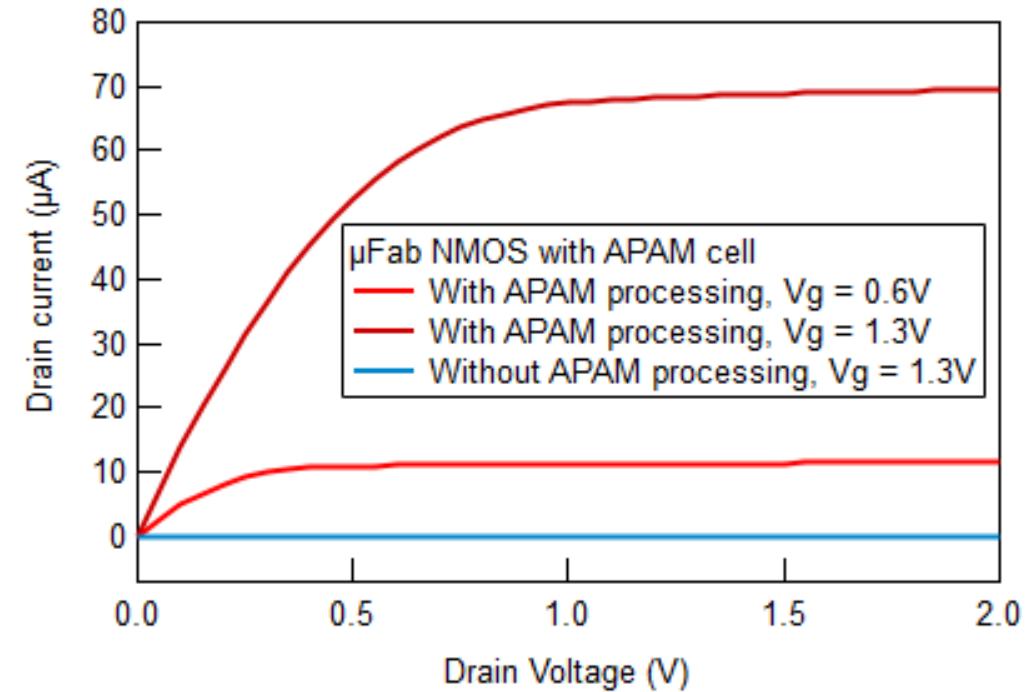


Drive gate of NMOS transistor with APAM cell

Blue: nothing

Brown: metal wire

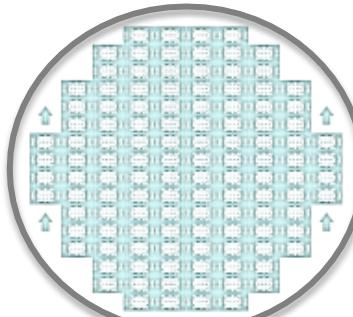
Red: APAM wire



Semiclassical and circuit modeling used to design CMOS circuits, understand impact of APAM processing and devices

**We have succeeded in integrating APAM with CMOS**

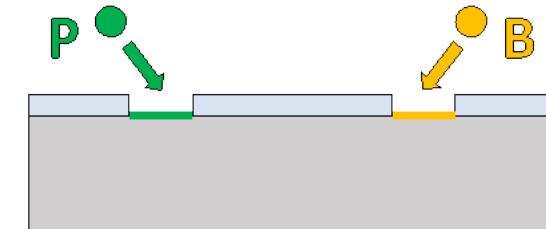
# APAM toolbox



Wafer-scale  
lithography



Application pull – CMOS contacts



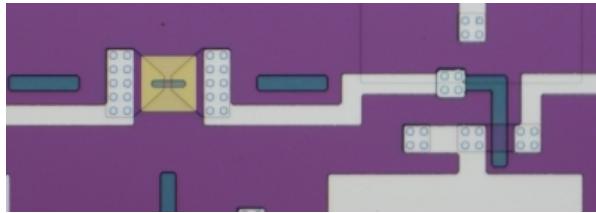
Acceptor precursor discovered



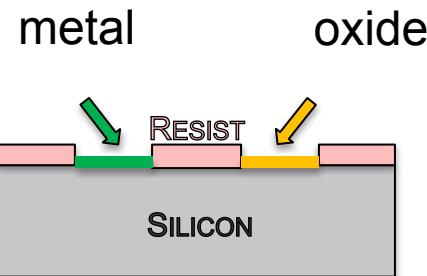
**Path forward for manufacturability  
Able to expand APAM chemistry**

# Other major technical accomplishments

## A. Microfab integration platform

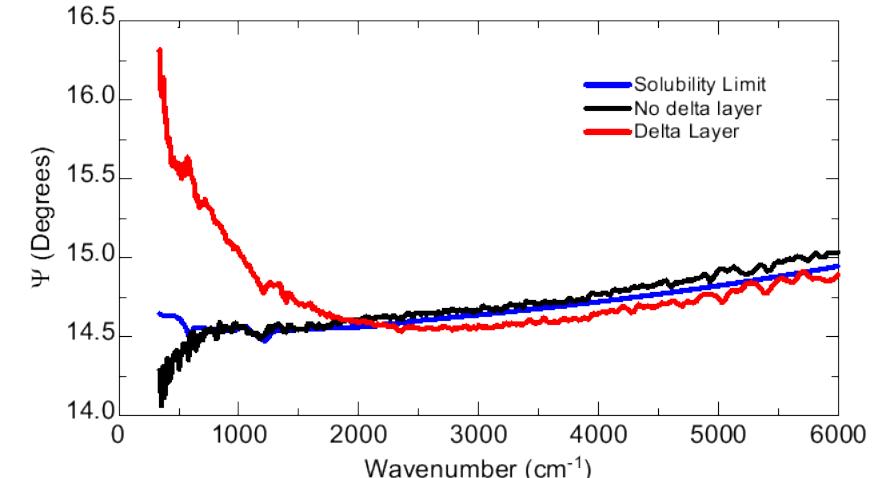


## B. Expansion of APAM-compatible chemistry

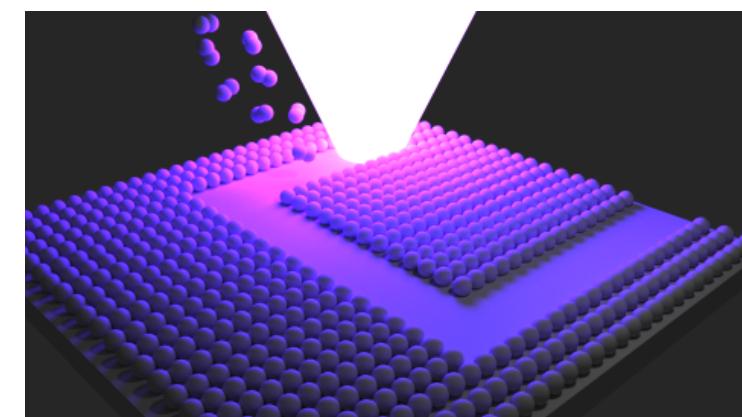


The logo consists of a large yellow 'R' on the left and the letters 'LPS' in blue on the right, all in a bold, blocky font. A small registered trademark symbol (®) is located at the bottom center of the 'R'.

### C. Optical response of APAM



#### D. Hydrogen photolithography



# Sandia and partners are in a leading position

## Output

### Thrust 1: APAM-enabled Devices

- 1 technical advance
- 5 published papers
- 1 book chapter
- 4 papers in preparation

### Thrust 3: CMOS Integration

- 1 patent
- 1 technical advance
- 1 published paper
- 4 papers in preparation

### Thrust 2: APAM Modeling

- 3 papers published
- 2 papers in preparation

### Thrust 4: APAM toolbox

- 1 patent (photolitho)
- 6 published paper
- 5 submitted papers
- 6 papers in preparation

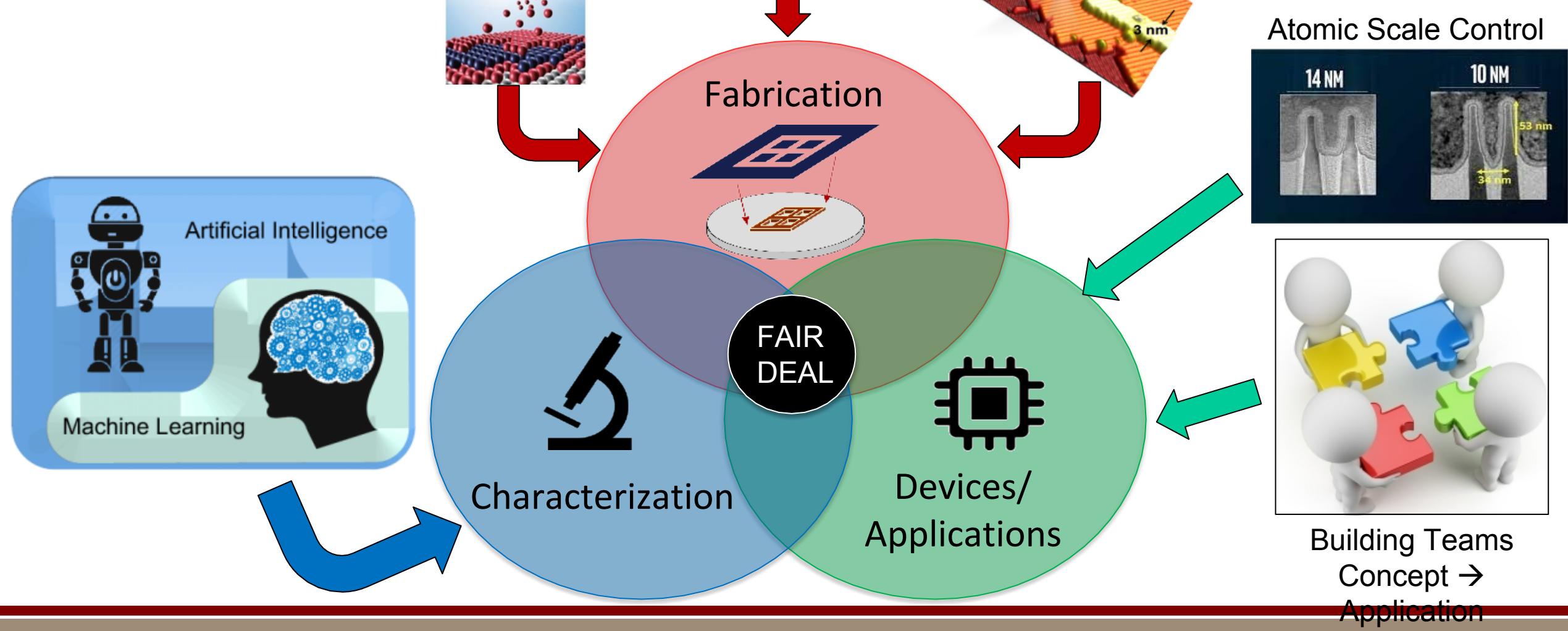
## Partnerships



IEEE, Physical Review, Journal of Material Research, SPIE, J. Physical Chemistry, Langmuir

NYU, Columbia, BNL, APL

# April 2021 Workshop



# Staffing accomplishments

**Program Leadership**

PI: Shashank Misra  
PM: Robert Koudelka  
Deputy PM: Paul Sharps  
Dir. Champion: David White

**APAM-enabled devices**

Lead: Shashank Misra

**Integration**

Lead: David Scrymgeour

**Modeling**

Lead: Suzey Gao

**APAM toolbox**

Lead: George Wang

**Support Team**

Financial: Jennifer Woodrome  
Logistics: Jennifer Woodrome  
Web: Jennifer Woodrome  
IP: Marty Finston

Measurement: Lisa Tracy, Tzu-Ming Lu, Albert Grine, Connor Halsey, Ping Lu, Aaron Katzenmeyer, Chris Allemand

Microfabrication: Andrew Leenheer, DeAnna Campbell, Mark Gunter, Phillip Gamache

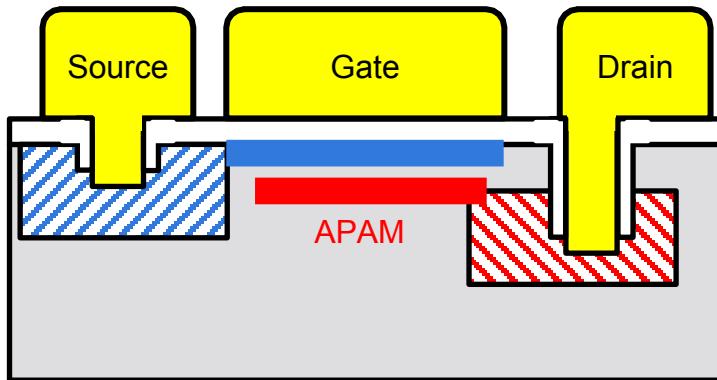
Modeling: Denis Mamaluy, Juan Granado, William Lepkowski, Andrew Baczewski, Quinn Campbell, Steve Young

Surface Science: Scott Schmucker, Evan Anderson, Jeff Ivie, Ezra Bussmann, Fabian Pena, Aaron Katzenmeyer, Esther Frederick, David Wheeler

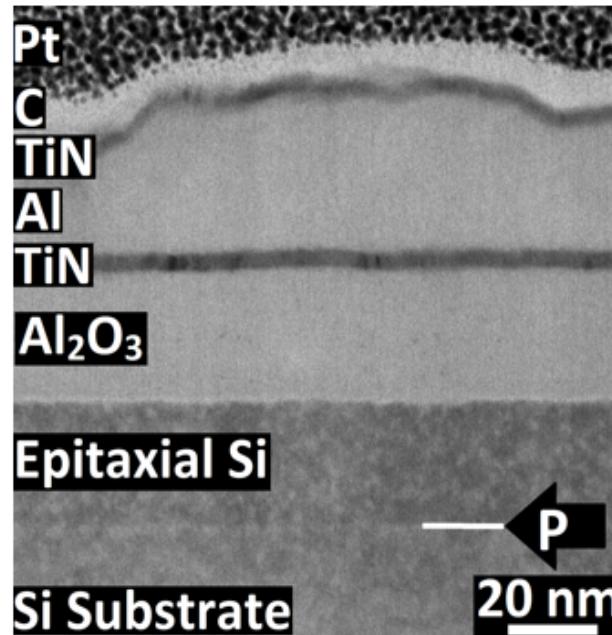
Underlined = new hire, or promoted

# Outline

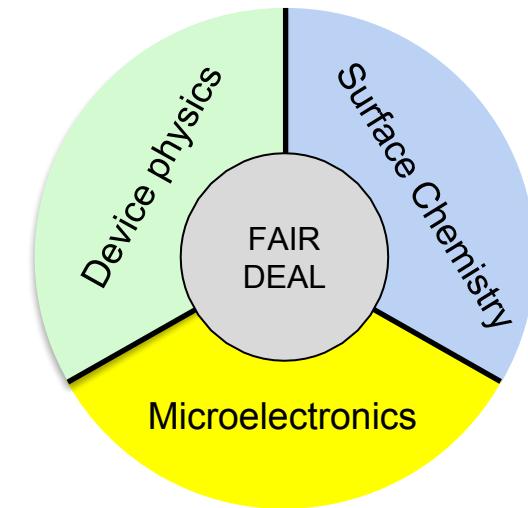
## 1. Goals



## 2. Accomplishments

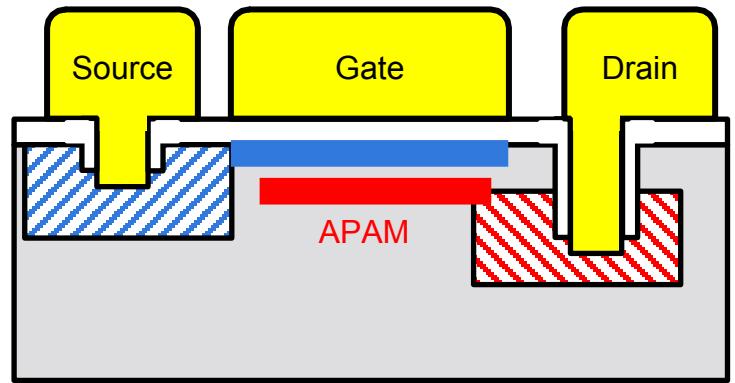


## 3. Our future

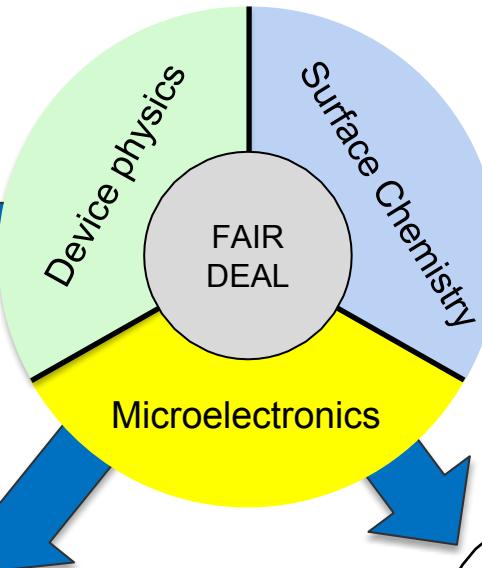
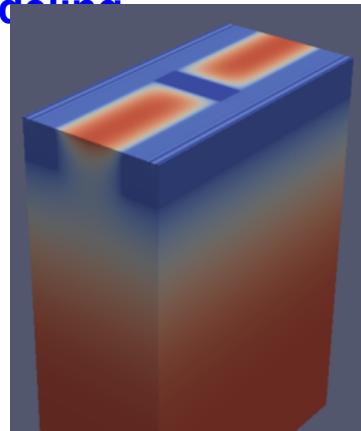


# Where do we go from here?

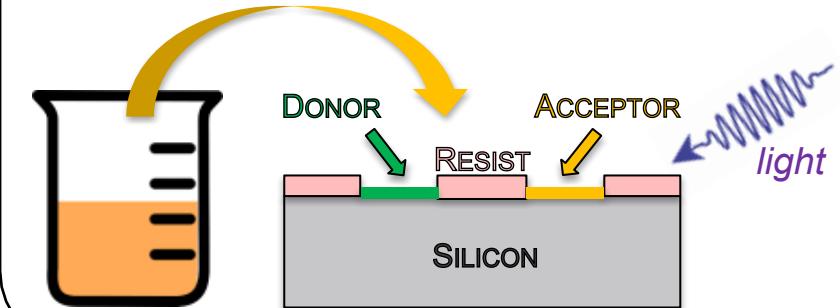
## Thrust 1: APAM-enabled Devices



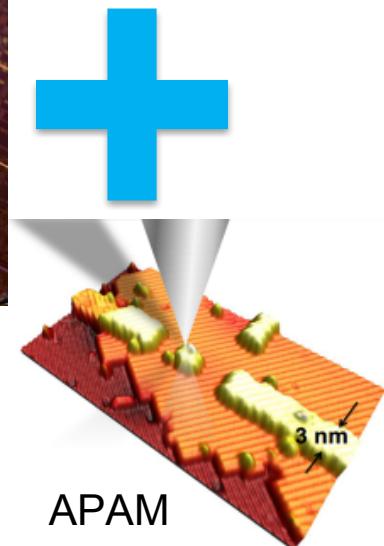
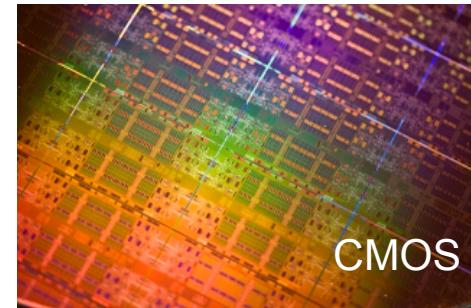
## Thrust 2: APAM Modeling



## Thrust 4: manufacturability



## Thrust 3: CMOS Integration

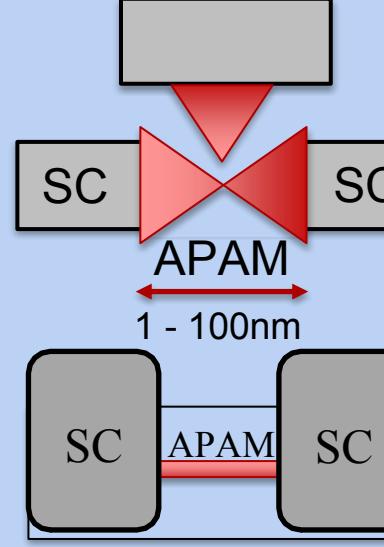
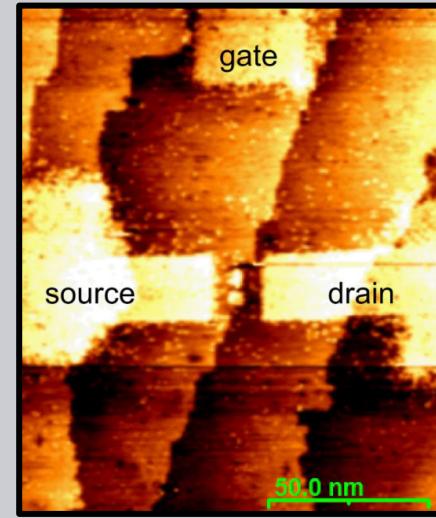
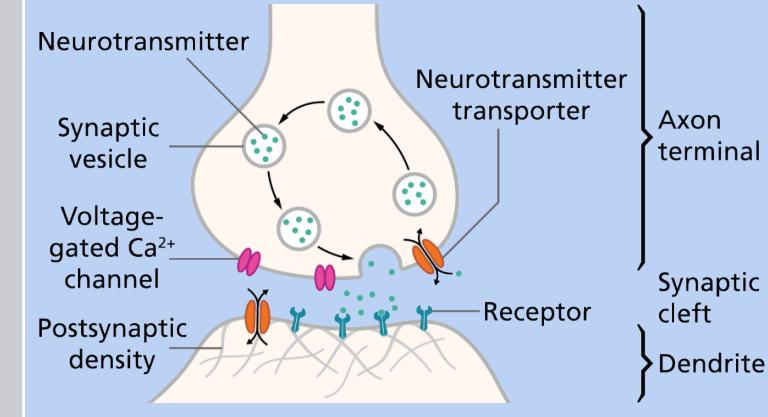


FAIR DEAL established a science and technology foundation. TRL 1→3

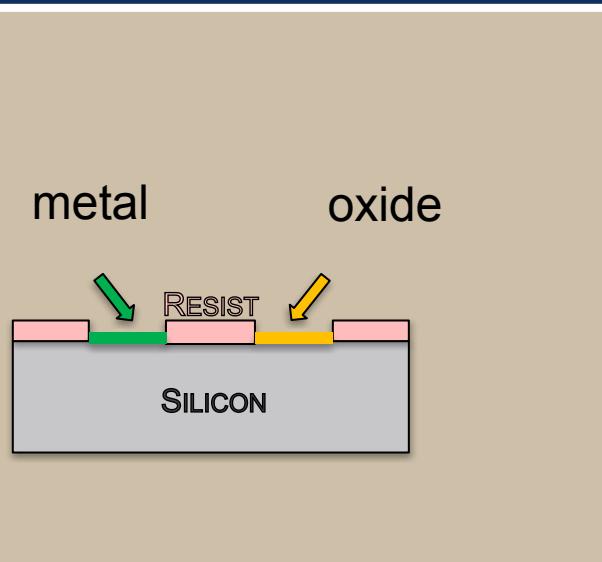
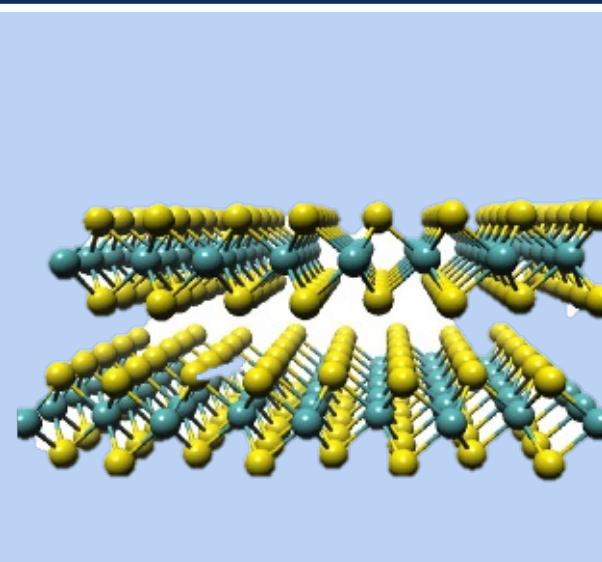
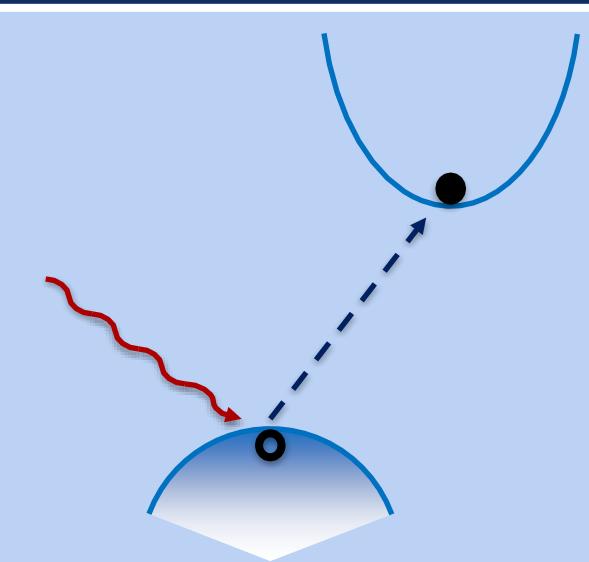
Next: Build applications on that foundation & expand the science of APAM based on what we learned.

# New Science



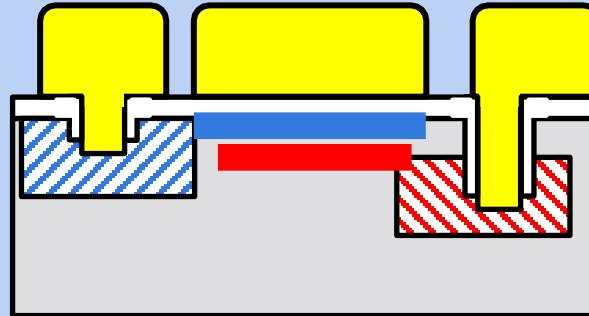
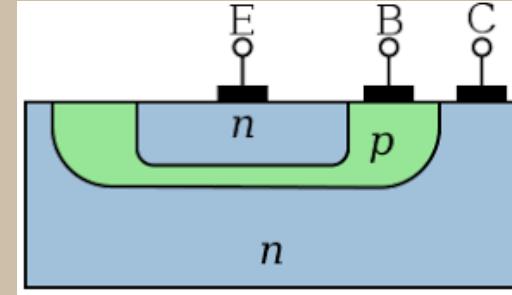
Name	Super/semi qubits	Room temperature SET	COINFLIPS
Blue = day 2 Brown = day 1 Gray = skip	 <p>Overhead view</p> <p>Cross-Section</p>		
Description	Gated superconducting devices	Electrometer for sensing	Probabilistic computing paradigm
Agency	DOE/BES & ARO	ARO	DOE/ SC & SNL LDRD
Dollars	\$250 k / \$800 k	\$800 k	\$500 k / \$125 k
TRL	2→3	2→3	1→2 (codesign)
Science goal	Superconductivity in APAM & understanding defects	Tunneling & temperature	Understand defects in tunneling & random number generation
Builds on	Thrusts 1 & 2	Thrusts 1 & 2	Thrusts 1 & 2

# New Science

Name	APAM + ALD/ALE	2D Materials	Optoelectronics
Blue = day 2 Brown = day 1 Gray = skip			
Description	Atomic-scale ALD & ALE	APAM on 2D materials	Optically active silicon
Agency	USG	SNL LDRD	SNL LDRD
Dollars	Whitepaper in progress	\$125 k	FY 22 idea
TRL	2→3	1	2→3
Science goal	Expand chemistry & understand non-ideal environments	Rules for what materials you can do APAM on	Expand chemistry & understand band structure
Builds on	Thrusts 2 – 4	Thrust 4	Thrusts 2 – 4

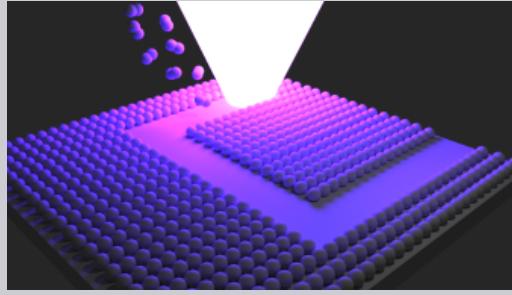
# Applications



Name	BEETS	Hardware Trust	BJT Amplifiers
Blue = day 2 Brown = day 1 Gray = skip			
Description	Energy efficient transistor	Reconfigurable circuit	High gain*bandwidth amp
Agency	DOE/AMO	SNL LDRD	DOE/ AMO (Zyvex Labs)
Dollars	\$500 k	\$500 k	\$125 k
TRL	3→4	2→3	2→3
Technology goal	Proof-of-concept demonstration	Assessment	Modeling-based projection
Builds on	Thrusts 1 & 2	Thrusts 1 – 3	Thrust 2

# Applications



Name	Fingerprint	Contact Resistance	Photolithography
Blue = day 2 Brown = day 1 Gray = skip			
Description	Supply-chain assurance marker	APAM-infused CMOS contacts	Atomic resist for EUV
Agency	USG	Applied Materials	SNL LDRD / LBNL
Dollars	Whitepaper in progress (small)	Proposal in progress (very small)	FY 22 idea
TRL	2→4	Hard to tell. Perhaps 3→4	2→4
Technology goal	Proof-of-concept demonstration	Determine impact of world-record dopant density	Compare to leading resists in EUV tool
Builds on	Thrusts 1 – 3	Thrusts 1 – 4	Thrust 4

# Conclusion

- The perspective from January 12, 2018.
  - Science & technology risk in an application-driven world
- We have a path forward.
  - FAIR DEAL was ~ \$5 M/yr
  - \$4 M in proposed/funded work for FY 22.
- The future remains uncertain.
  - What are we missing?

